



FOR IMMEDIATE RELEASE

ISSYS Inc. Awarded a Patent for Wireless, Batteryless, Implantable Sensors

Ypsilanti, Michigan, July 5, 2007: Integrated Sensing Systems, Inc. (ISSYS) announced that the U.S Patent Office has granted a patent entitled “System for monitoring conduit obstruction” (US Patent No. 7,211,048) which covers the design and manufacturing of a wireless implantable sensing system for non-invasive monitoring of pressure and/or pressure gradients in a cardiac conduit.

Certain heart defects require implantation of a cardiac blood flow conduit in order to bypass valve aplasia or severe stenosis. One of the main issues with implanted cardiac conduits is that over time calcification or stenosis will occur and, in nearly all cases, occlusion will occur eventually. ISSYS’ novel implantable wireless sensing system allows physicians a means for accurate and non-invasive monitoring of conduit condition on a continuous basis. Using the data provided by ISSYS’ sensors, physicians can continuously monitor both pressure and blood flow rate within the conduit, in order to determine whether and when conduit revision is required. Furthermore, remote monitoring of conduit condition would simultaneously reduce the number of hospital and clinic visits while increasing the overall timeliness of treatment.

Dr. Nader Najafi, ISSYS CEO, stated that “ISSYS has already established a solid patent portfolio to cover the design and technology of its wireless implant platform. It is exciting to see that the recently awarded patents are now covering the medical applications of our technology.” ISSYS technology supports the trend towards home health monitoring and has the potential to revolutionize the way many diseases are treated. The particular targets of ISSYS products are cardiovascular disease, especially congestive heart failure, hydrocephalus (high brain pressure), and traumatic brain injuries.

Company Background: ISSYS is a leader in advanced micromachining technologies for medical devices, microfluidic and scientific analytical sensing applications. Founded in 1995, ISSYS is one of the oldest independent MEMS companies in the US. ISSYS operates a “full manufacturing under one roof,” multi-million-dollar, state-of-the-art MEMS fabrication facility located near Ann Arbor, Michigan. An ISO 9001:2000 certified organization and ISO 13485 qualified, ISSYS is a vertically integrated company dedicated to developing and manufacturing system-level products based on MEMS technology (MEMS Inside). For more company, product and service information, please visit <http://www.mems-issys.com/>

Source: Integrated Sensing Systems, Inc. (ISSYS)

Contact: Dr. Cathy Morgan
Integrated Sensing Systems Inc. (ISSYS)
391 Airport Industrial Dr., Ypsilanti, MI 48198
Tel: (734) 547-9896 Ext. 118
Fax: (734) 547-9964
Email: cmorgan@mems-issys.com